

Title (en)

A METHOD AND APPARATUS FOR DEPOSITING A MICROCRYSTALLINE MATERIAL IN PHOTOVOLTAIC APPLICATIONS

Title (de)

VERFAHREN UND VORRICHTUNG ZUR ABSCHIEDUNG EINES MIKROKRISTALLINEN MATERIALS BEI PV-ANWENDUNGEN

Title (fr)

PROCÉDÉ ET APPAREIL POUR DÉPOSER UNE MATIÈRE MICROCRISTALLINE DANS DES APPLICATIONS PHOTOVOLTAÏQUES

Publication

EP 2558612 A1 20130220 (EN)

Application

EP 11716460 A 20110414

Priority

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- CH 2011000080 W 20110414

Abstract (en)

[origin: WO2011127619A1] A deposition method and system for producing a photovoltaic cell is provided. The method includes maintaining a sub-atmospheric pressure within a reaction chamber during at least a portion of the deposition of the semiconductor material. The distance D separating the first and second electrodes is expressed in mm, and is greater than or equal to about 10 mm but less than or equal to about 30 mm. A concentration of the semiconductor-containing gas in the process gas of at least fifty (50%) percent by volume is established during at least a portion of the deposition of the semiconductor material.

IPC 8 full level

C23C 16/24 (2006.01); **C23C 16/455** (2006.01)

CPC (source: CN EP KR)

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Citation (search report)

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